

<b>Notice of References Cited</b>	Application/Control No. 10/535,270	Applicant(s)/Patent Under Reexamination NEWKIRK ET AL.	
	Examiner Qiuwen Mi	Art Unit 1655	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2001/0018197	08-2001	Wong et al.	435/68.1
*	B	US-5,834,286	11-1998	Nevalainen et al.	435/196
*	C	US-5,096,594	03-1992	Rabinowitz, Israel	210/656
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.